Mahr | 3D microscopy and profilometry



# **Optical metrology** for surface analysis



Mahr | Optical metrology

## **Optical systems** for your surface analysis

Maximum precision, modern technologies and a worldwide presence – this is what Mahr stands for. As a manufacturer of innovative production metrology, we have been supporting our customers for more than 160 years, in the measuring room, in production, and with their research and development. All of our products are built on the passion and expertise of the 1800 Mahr employees. This also applies to our optical measuring technologies: Our range includes confocal systems, profilometers, right through to the white light interferometer series with its highly innovative ICA algorithm. This ensures that exactly the right system is available for every optical measuring task and every surface. Our experts work with you to determine which measuring technology is best suited to your tasks.

## Advantages of optical systems

- Three-dimensional
- Contactless
- Standard-compliant
- Material-independent surface detection
- High measuring speed
- Resolution into the subnanometer range
- Easy to handle

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## Your surfaces in focus

Optical 3D metrology | Measuring tasks at a glance

To ensure each component exhibits the maximum performance, the surfaces must often have special characteristics. That applies to form deviations and roughness as well as waviness or geometric features.

Only then do components qualify for further processing – otherwise they are discarded immediately. Powerful Mahr metrology provides you with the entire portfolio of characterization options based on precise measuring data. The topographical analyses range from particle analysis to angles, right down to the determination of layer thicknesses. This allows you to detect potential errors and take counteract any waste during continuous production.

#### 3D roughness (Sa, ...)

Extensive roughness evaluations as per ISO 25178

#### 2D roughness (Ra, ...)

Profile roughness in accordance with ISO 4287, ISO 13565, ISO 21920, ASME B46.1,ISO 12085, SEP, VDA guidelines, and other standards

#### Profile trace errors ( $\frown$ )

Linear errors compared to a target contour as well as straightness parameters as per ISO 12780

#### Contour analysis ( ≮,R)

Determining radii, circles, segments of a circle and angle determination including evaluation of half or full angles



Determining the flatness of a full or partial surface, e.g. in accordance with ISO 12781

# <image>

Particle analysis

**Visual inspection** 

## Volume (V)

Volume calculations of hollows, hills, valleys, peaks, and particles

#### Distance measurements ( $\Delta$ )

Comprehensive horizontal distance measurements (x;y), angle positions and inclinations

#### Form

Form deviation from planar contours, target/actual comparison with CAD data, roundness evaluation in accordance with ISO 12181

#### Error

Detection and analysis of defects, surface imperfections and damage

#### Layer thickness

Direct determination of the thickness of transparent layers, step height analysis of opaque surfaces

#### Height ( 🗠 )

Distance measurements (z), determination of maximum and average heights as well as differences in position

#### Area (A)

Calculation of surface area in peaks and hollows as well as determination of maximum elevations/depressions



Applications | 3D metrology

# **Sectors** and applications

Surfaces are becoming increasingly complex due to new manufacturing processes, new production processes, and new materials. To ensure that your structures and topographies are exactly right and meet the required values, Mahr offers a wide range of areal 3D surface metrology – and guarantees to have the right device for your measuring tasks. Regardless of whether it is stationary or mobile, 2D or 3D, Mahr will always ensure that the quality is right.

# An eye catcher that is functional

Surfaces can be fascinating. They captivate you with flawless optics or well-developed haptics, for example, when things are pleasant to touch or lie comfortably in the hand. Operating elements and design surfaces, for example, thus have special textures that are achieved by blasting, polishing, etching, and using a laser. The spectrum ranges from finely structured housing surfaces made of metal with a homogenous appearance, through to rough plastic, or leather patterns made of distinct embossed structures.

Optical measuring systems are particularly used for development and quality control processes: They check the surfaces of tool inserts during production and the final products for consumers.

## The most common measuring tasks

- Isotropy
- Structural evaluation
- Waviness
- Roughness





Topography of a lock handle



Surface of a switch



Embossed structure of artificial leather

## The prototype for perfection

When it comes to implants for the human body, no amount of work is too much and no quality checks are too accurate. All of the manufacturing processes are monitored and the production systems are set accurately. This is why manufacturers of medical implants depend on reliable key figures.

The optical 3D measuring systems from Mahr supply fast and highly accurate results – regardless of whether this relates to the measurement of complex geometries on dental implants, the roughness measurement on hip prostheses polished to the nanometer, or on roughened products used for trauma surgery. The high level of reproducibility and accuracy of measurements, that can be traced back to international guidelines and standards, ensures that it is not just polishing and blasting processes that you can monitor safely.



## **Dental prosthesis**

Geometry of the roughened surface of a dental screw





## Hip joint

Carbides on an artificial hip joint

## Knee joint

Polished articulating surface of a knee implant

## The most common measuring tasks

- Roughness 2D/3D
- Complex geometries
- Pore and particle analyses

# The start of new drive technologies

Regardless of whether it is a hybrid, fully electric, or powered with hydrogen: The triumph of alternative drives on our roads can no longer be stopped. These drives place new challenges on the quality of the component surfaces.

Optical measuring systems from Mahr ensure that every element has a perfect degree of roughness and is located in the correct position. Mahr metrology supports you from development right through to the production-related quality assurance process. This means that alternative drives can get off to a reliably good start.

Fuel cell

Bipolar plates are the core of fuel cells. Stacked in layers, they provide precise energy flows, are safe to operate, and are thus ensuring the drive technology of the future. Bipolar plates place the highest demands on measuring technology: Roughness, geometry, form deviations, right through to the calibration with CAD models – everything must fit perfectly with nanometer precision.

## The most common measuring tasks

- Geometry und microgeometry
- Roughness
- Fault detection
- Particle analysis
- · Porosity



## Battery

To ensure that electric vehicles can achieve a high range, batteries with the highest possible energy density must be installed. One way to achieve this is a targeted structure of the electrode material. Different elements of the batteries are protected with an insulating varnish to prevent short circuits and increase safety. The coating thickness of just a few millimeters is particularly important. The roughness, porosity, and coating processes can be monitored using optical metrology, leading to savings on material and energy costs.



## Electric motor

The core of electric motors are rotors and stators. The production of the stator made up of electric sheets and induction coils is particularly complex. Optical metrology from Mahr can be used to determine the surface roughness of the housing and stator, which is important for the joining process. If the stator is impregnated with resin, then the coating thickness is checked in addition to the surface quality.

## Housing and sealing surfaces

In conjunction with the electrification of the power train, the operational safety and durability of the installed high-performance electronics must be ensured. To prevent contact with liquids and any possible chemical reactions, nowadays the contact surfaces of housings and sealing surfaces are ground in such a way that they are positively connected and are permanently sealed. Inspecting the surface structures using optical systems from Mahr enables the measurement of profile depths, angles and processing increments.

## **Providing the** right overview

Modern production processes, such as die-casting, laser ablation, and lithography processes, enable high-quality micro-optics to be produced for the telecommunication sector, medical technology, or camera technology in very large quantities. As every deviation distorts the optics, the process-related checking of the microgeometry and surface roughness using 3D measuring systems from Mahr is indispensable. Microlenses for smartphone cameras, for example, are tested to check their dimensional accuracy. The radius of curvature is accurately measured within the nanometer range and the slightest deviations are detected.

### The most common measuring tasks

- · Form deviations
- Roughness 2D/3D
- Defects



Form deviation





# Providing a smooth **flow of information**

Regardless of whether in the mobility or communication sector, or in the household: Miniaturized components, such as highly complex printed circuit boards (PCB/FPC), have long been part of our everyday life. They are produced using different printing processes. In addition to checking for any form deviations, the structure height must also be analyzed accurately. If the components are made of ceramic substrates, measurements must be completed before and after the burning process. There is even a trend to minimize semiconductor elements, which provides a challenge for measuring devices. A higher lateral and axial resolution must be guaranteed, which can easily be achieved using the different optical technologies from Mahr.

## The most common measuring tasks

- Structure height, contour, layer thickness
- Coplanarity
- Flatness und probe bend





Solder bumps and circuit paths on PCBs





Unevenness of the ceramic substrate and thickness of the printed-on silver coating

# From steel panel to highly complex body work

Steel has not just been steel for a long time. Modern thin sheet metals are real high-tech products, and their surface structure has a significant impact on the subsequent production. It is thus meticulously analyzed during all processing steps.

This starts with the optimization of the rollers that are used to structure the surface of the sheet metal. The focus is placed on setting the required surface parameters, detecting defects, and checking for wear.

In the body work sector, the structure of the sheet metal surface also has a significant impact on the shaping process and other process steps such as painting, and ultimately on the appearance of the final product.

## The most common measuring tasks

- Roughness
- Defects
- Wear/volumes
- Longitudinal waviness (SEP1941)



Topography of a hot-dip galvanized sheet metal



Structuring sheet metal using a roller







Roller topography

Sheet metal topography

## **Complex structures,** maximum flexibility

The production of components using 3D printing has increased incredibly. Workpieces are not only produced using an abrasive process but are also produced directly in one piece. This promises to provide great savings potential and significantly increase flexibility, especially for complex components. The performance, however, must be right. The component quality may in no way be inferior to conventional processes. The surface quality of many components is significant for ensuring their long-term function. Mahr's optical metrology offers flexible solutions for fast determination of the necessary surface quality and required tolerances.

## The most common measuring tasks

- Surface quality/roughness
- Geometry
- Step height
- Form deviation





X-ray lenses



Gear



Mahr | Comparison of measuring technologies

# Measuring using the right technology

Do you need to measure roughness frequently? Do you value a fast measuring time when capturing large areas? Or do you require a high level of dynamics to measure geometries? Regardless of what is important to you: Mahr can provide you with a full range of technologies for all measuring tasks. The following comparison of the technologies provides you with an initial overview of the systems, making the selection easier.

## **The right technology** for every measuring task Patented confocal technology

The robust MarSurf CM sensor technology is based on the patented Confocal Multi-Pinhole (CMP) technology. The light of a LED light source shines through the pinholes of a multi-pinhole disc (MPD) and is focused through the objective lens on to the surface of the specimen. The specimen reflects the light beams back to the measuring device. At every pinhole of the MPD, the reflected light is then reduced to the focused part. The rotation of the multi-pinhole disc ensures that the surface can be scanned fully. This principle prevents the scattered light from adjacent measuring points interfering with the camera pixels. When combined, these individual values provide the confocal curve from which the precise height value of a pixel is determined.



#### Typical structural sizes

Confocal



#### Confocal | MarSurf CM





## High precision white light interferometry

The MarSurf white light interferometers are based on the Mirau or Michelson principle, depending on the objective lens. Coherent light from a light source is split into a measurement and reference beam by a beam splitter. The measuring object reflects the measuring beam, while the reference beam is superimposed with the measuring beam via a mirror. A correlation diagram is generated from the intensity progression from which the new Mahr Intelligent Correlation Algorithm (ICA) determines the height values of the pixels.





# The right process for your requirements

## Profilometer with point sensor

Typical structural sizes

The diffraction of white light in different wavelengths is used when recording measuring values to determine the height. Each of these wavelengths is assigned to a height value via a spectrometer.





#### Point sensor | MarSurf CP

| Roughness |      | Geom  | Flatness |   |  |
|-----------|------|-------|----------|---|--|
| Rough     | Fine | Macro | Micro    |   |  |
| •         | •    | •     | •        | • |  |
| •         | •    | •     | •        | • |  |
|           | 0    |       |          |   |  |



## Profilometer with linear sensor

With the chromatic linear sensor CL, 192 points are focused along a linear line of the surface of the measuring object. The reflected light for each of these 192 channels can be analyzed spectrally and thus used to determine the height.





## Maximum process stability thanks to superior data quality

Measurements are not all the same – it depends on the quality of the data! It is best to get direct advice from a Mahr expert, who will be able to tell you exactly which optical technology, such as profilometry, white light interferometry, or confocal measurement method, is best suited to your requirements.



#### Measuring equipment functionality for the step height

## Highest repeatability

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Patented hardware solutions, such as the multi-pinhole disc on the MarSurf CM, and innovative algorithms, such as the ICA evaluation of the MarSurf WI series, ensure that you always achieve the best possible quality of data. They stand for robust measurement data acquisition and stable measurement data evaluation and lead to maximum repeatability.

## Minimum measuring uncertainty

All Mahr measuring instruments are accepted based on certified standards in accordance with strictly specified criteria from the valid ISO 25178 standard. This ensures minimum measuring deviations and the traceability of the results. You can be certain that your products will have the exact properties you expect.

## ISO

## Specifications at a glance

Mahr has committed to observing the Initiative Fair Data Sheet. This means that all device properties are in a comprehensible and comparable format. By selecting high-quality components and accurate production processes, we ensure that Mahr measuring systems always meet the specifications.

Fair **Data Data Sheet** 

high

Jncertainty

NO



10

The high quality of our measuring instruments 'Made in Germany' ensures an excellent level of repeatability of all measurements and stands for the verified functionality of the measuring equipment. For you as the user, this means maximum precision and minimum uncertainty.

The cg capability index was used to measure the level of repeatability.

Step height (µm)

• Formula cg = 0.2 \* T / (6 \* s)

100

- Tolerance T = 10% of the step height
- MarSurf CM and MarSurf WI with 20x objective lens, laser scanning systems with 20x/50x, focus variation "xxx"



MarSurf | Software solutions

## Measure, display, evaluate

With the comprehensive software solutions from Mahr, you will have valid data in no time at all. It does not matter if you are using profilometry, white light interferometry, or confocal measuring systems. A variety of automation options for user-independent series measurements, customer-specific evaluations, and an unlimited number of measuring positions extend the range, while all still adhering to the usual high level of precision provided by Mahr.

# One software, all measuring systems

Regardless of which measuring system from Mahr you choose, you will probably already be familiar with the software that comes with it. For all systems in the MarSurf 3D series, Mahr relies on the same, clearly structured software design that has proven itself many times over in practice. The Mahr software consists of several components that work together perfectly. They provide you with an intuitive application that delivers fast and accurate results. Consistently high data quality is also guaranteed on large measuring surfaces.





Metrology Suite

#### MarSurf | Metrology

## Intuitive measuring

The measurement and control software -MarSurf Metrology – ensures the efficient execution of all measurements

- Fast overview image (pre-scan function)
- Access the measurement in just a few clicks (snapshot technology)
- Multiple measurements can easily be completed (Multi-Spot Tool)
- Automatic setting of the measuring range (auto range)
- All parameters are saved as a template for repeat measuring tasks (template function)

#### MarSurf | MfM

# Effective display and evaluation

Display and document structures, roughness, waviness, and much more using the MarSurf Mountains from Mahr

- Fast and high-quality 3D overview
- O User-independent
- Can be automated
- O 3D analysis, ISO 25178, ISO 13565, ISO 12781...
- O 2D analysis, ISO 4287, ISO 21920...
- O Geometry, volume, contour, CAD comparison

#### MarSurf | Automation

# Individualized automation

Automate measurements and evaluations using the MarSurf Automation software

- O User-independent serial measurements
- Rights management
- O Record creation and SPC
- O Registration mark detection and specimen position
- O Information input using barcode/data matrix code
- O QS-STAT output







## One user interface, many functions

With the user-friendly measurement and control software – MarSurf Metrology (MSW) – all sensors and the overview camera can easily be controlled from one user interface. When switching between measuring heads, the selected measuring head automatically moves to the defined measuring position. Meaningful 3D overviews of the measuring results, including intensity overlay, are already available after just a few seconds.



## Measuring intuitively

The measurement and control software – MarSurf Metrology – ensures the efficient execution of all of the measurements



## Navigator function

The navigator function generates a fast overview image, in which the required measuring range can easily be selected using the mouse.

| Measurement settings |                 |         |               |      |  |  |
|----------------------|-----------------|---------|---------------|------|--|--|
| +                    |                 |         | Save          |      |  |  |
| $\rightarrow$        |                 |         | Load          |      |  |  |
| +                    |                 |         | Default setti | ings |  |  |
|                      |                 |         |               |      |  |  |
|                      | Multi Spot Tool |         |               |      |  |  |
|                      | X               |         | Υ             | z    |  |  |
| ►L.                  |                 | 111.371 | 151.955       |      |  |  |
| 2                    |                 | 115.302 | 152.356       |      |  |  |
| 3                    |                 | 114.577 | 154.878       |      |  |  |
| 1                    |                 | 112.178 | 153.895       |      |  |  |

## Template function

The template function can be used to save measuring parameters as a template. Recurring measuring tasks can thus be implemented easily.

| 1 (  | 9  | <b>Objective</b><br>800XS (20x / 0.60)    | Working distance<br>1 mm      |
|------|----|---|-------------------------------|
| 2 -] | ¢- | Brightness<br>Auto                        | Exposure / Gain<br>40 ms 0 db |
| 3    |    | Measurement field.<br>0.800 mm x 0.800 mm | XY                            |
| 4    | 4  | Measurement Z<br>Auto                     | Range<br>107.8 µm             |
| 5    |    | Parameter                                 | Algorithm<br>Standard HDR     |
| 6 [  | •  | Output<br>NarSuit Metrology SW            | Data processing               |

## Snapshot technology

After you have arrived at the desired sample position, simply click for optimum measuring results. The MarSurf MSW automatically regulates all of the settings, including the focus range and brightness. At the same time there is enough room for individual settings.

## Multi-Spot Tool

With the MarSurf Metrology software, you can approach several measuring positions individually, save them, or define them directly in the navigator overview. Alternatively, a fixed grid can be copied to the points, or a temporal instead of a local offset can be used at that point for the repeat measurement to monitor any changes. All points are recorded and saved in one measuring process.

Measuring processes using the Multi Spot Tool can be saved as a template for subsequent measurements. The tool includes all of the known, easy-to-use functions of the MarSurf MSW, including the Auto-Range and Stitching functions. Semi-automated processes can also be designed.

| Meas | urement setting | js            |        |        |  |  |  |  |  |
|------|-----------------|---------------|--------|--------|--|--|--|--|--|
| +    | ♦ Save          |               |        |        |  |  |  |  |  |
| +    | + Load          |               |        |        |  |  |  |  |  |
| +    |                 | Default setti | ings   |        |  |  |  |  |  |
|      | Multi Spot Tool |               |        |        |  |  |  |  |  |
|      | х               | Y             | Z      | Repeat |  |  |  |  |  |
| 1⊧1  | 110.316         | 149.249       | 1.7459 | 1      |  |  |  |  |  |
| 2    | 115.319         | 151.273       | 1.7450 | 1      |  |  |  |  |  |
| -    | 114.403         | 149.203       | 1.7459 | 1      |  |  |  |  |  |
| 4    | 120.811         | 153,417       | 1.7450 | 1      |  |  |  |  |  |
| -    | 119.103         | 151.525       | 1.7459 | 1      |  |  |  |  |  |
|      |                 |               |        |        |  |  |  |  |  |





**Roughness as per** ISO 25178, ISO 13565, ISO 4287, ISO 21920



Particle/pore analysis including classification Height/depth, area, volume, diameter



Flatness as per ISO 12781



Geometry and contour evaluation in 3D



90.1 •

3000 3500 4000

Geometry and contour

evaluation in 2D



Nominal/actual value comparison using GOM Inspect

# Surface characteristics at the press of a button

The surface analysis software MarSurf Mountains for Mahr offers a comprehensive function package, which is required to display and analyze the structure, roughness, waviness, step height, contours, and other surface characteristics. The clearly structured, multilingual user interface makes it possible to create complex analytical reports at the touch of a button. A variety of display options, such as profile view, 3D reconstruction, or a reflectance image provide informative measuring records. It is easy for users to create individual evaluation template.

The software always contains the most up-to-date standard parameters and filter functions. It is available in the Standard, Extended, and Premium versions. Special modules, for example for particle analysis and individual evaluations, can also be integrated.



## Effective display and evaluation

Display and document structures, roughness, waviness, and much more using the MarSurf Mountains from Mahr



Edit ---> Wide range of operators to:

- Remove form
- Select
- Filter

| Heigl | nt param | eters |                         |
|-------|----------|-------|-------------------------|
| Sq    | 0.16     | μm    | Root-mean-square height |
| Ssk   | -0.30    |       | Skewness                |
| Sku   | 6.61     |       | Kurtosis                |
| Sp    | 1.14     | μm    | Maximum peak height     |
| Sv    | 1.07     | μm    | Maximum pit height      |
|       |          |       |                         |

- Roughness
- Geometry
- Tribology



**Document** Creation of individual templates:

- 2D and 3D images
- Profile
- Tables



Automate Use of created templates for repeat measuring tasks:

- MiniDocs
- Batch processing

# Measure, evaluate and automate

The MarSurf ASW software can be used to easily automate individual measurements and special, customer-specific special evaluations.

An unlimited number of measurement templates can thus be defined, for example, and saved in a database. They are then always ready to use. Users can define an unlimited number of measuring positions on every individual specimen and for every individual sensor setting. During series measurements, several specimens are approached and measured in the same way as an individual measurement. All specimens can be measured in the same way in accordance with the defined measurement settings. Evaluation features can also be defined specifically, activated,

or deactivated for each specimen.

## Database technology

The MarSurf ASW database technology has a comprehensive evaluation library. Measuring results and evaluations are stored on a continuous basis and are thus available for statistical process control. The central data base and templates stored within it can be accessed from several systems.

## Recording specimen information

- Recording order-specific information, such as the user ID, component type, batch number, date/time, etc.
- Manual input of the information
- Digital input using data matrix code reader
- Measurement templates are automatically linked to the respective evaluation templates based on the specimen information



## Can be automated individually

Automate measurements and evaluations using the MarSurf Automation software

## Suitable for industrial applications

The software meets current industrial standards by supporting registration mark detection and the transfer of measuring data to the statistic software (e.g., QS-Stat). The parallel recording and evaluation of measuring data by two computers is supported. A strict separation between user and administrator modes guarantees that it is very easy to operate and provides reliable results.

## Rights management

- Hierarchical user administration including password protection
- Rights assigned for operational, process, and administrator levels

## Series measurement

User-independent and automation

## 00000 00000 00000 00000

## Check specimen position

- Automatic detection and checking of the specimen position
- Optional correction using registration mark detection available
- Compensate for positioning inaccuracies when inserting the specimen
- Overcome component/size tolerances and corresponding correction of the measuring position



## Measurement

Start individual or series
measurements

## Evaluation

- Transfer of the measuring data to the analysis software and customer-specific algorithms
- Evaluation based on predefined evaluation templates or templates created by the user

| Mahr |  |
|------|--|
| × () |  |
| J J  |  |
|      |  |
|      |  |

## Creation of a measurement report

- Comprehensive overview of the measuring result by means of informative measuring reports
- Output via MS Excel or as a PDF file



## Multisensor system

The measurement templates support acquisition with multiple sensors. A defined and automatic switch between the sensors can be specified for this purpose.

## **Process control** via integrated statistic functions

The flexibility of the different statistical evaluations and graphic display options is vast. Differences between production lines or a reduction of the quality caused by the wear of tools can thus be detected quickly. Other advantages: Quantitative evaluations can be completed and are immediately visible.



#### Produce

Optical measuring technology has now become the global standard for monitoring the commissioning of new manufacturing processes and for production processes with several production lines.

#### Advantages Mahr has to offer:

- Avoiding waste
- Avoiding complaints
- Avoiding time consuming and complex subsequent processes
- Time and cost savings

#### Readjust

The process control can, for example, be used to detect the wear of tools at an early stage and thus enables tools to be replaced in good time. If differences are detected between different production lines, timely readjustments can prevent and reduce waste.



#### Check

Fast detection of significant changes to the production process with regard to the position and control, thanks to the graphic overview of the measuring results. By setting control limits, as well as upper and lower product specifications, you will always have control of your production process.



#### Measure

Optical measuring systems from Mahr are fast, contactless, and convince with the best data quality.

| Sku | Rpc | Sa | S10z | Svk |  |
|-----|-----|----|------|-----|--|
| Rpk | Rk  | Ra | Ра   | Sdr |  |
| Sq  | Wa  | Wt | Rz   |     |  |

#### Find the right parameter

We will happily support you in determining the informative parameters for your production process.

#### **Evaluate**

Integrated statistics functions make it easy to determine suitable parameters for process control.



#### Export

In addition to the internal statistic functions in the evaluation software, Mahr also provides an automatic export of the results in a format of your choice. Common interfaces, such as QS-STAT, are of course supported.


White light interferometry | MarSurf

## Minimal roughness down to the nanometer

Surface properties are becoming increasingly relevant in determining the performance of components and subsequent products. To help you measure these properties quickly and precisely to the nanometer, Mahr has now developed three powerful white light interferometers with a novel algorithm.

## **Record topographies** in the sub-nanometer range

The new white light interferometer series from Mahr comprises three high-performance devices: MarSurf WI 50 M, MarSurf WI 50, and MarSurf WI 100. They stand out for having a very large positioning volume for large workpieces and the intuitive user software that Mahr customers know and value from the optical systems.

#### Your advantages

- Intelligent Correlation Algorithm (ICA technology)
- Minimal noise figure
- High level of accuracy
- Maximum stability

### High-performance ICA technology

The new white light interferometers from Mahr are based on a new type of algorithm that combines the good properties of previous processes, such as PSI and VSI, in a single, large application range. This algorithm searches for the best correlation by comparing every single pixel. The calculated height values are very precise and robust. This minimizes noise, which consequently ensures unparalleled data quality. Laboratories and quality assurance processes can thus determine the finest roughness, step heights, or planes in the nanometer range in just a few seconds.

#### VDI/VDE 2655 | ISO 25178

Certified system acceptance

#### Low SNR

Signal/noise ratio on reference level

#### up to 5 MP

High lateral resolution with max. number of pixels

#### ICA technology

Intelligent Correlation Algorithm: Best correlation with minimum amount of noise

## 50,000 MTBF

0

0

0

0

5 sec. Typical measuring time for 3D

roughness measurement

0.13 μm

**O.O8** nanometer Noise figure as per STR

126,000,000 Measuring points per second





## **High-performance entry-level solution**

Precise measurement in the sub-nanometer range easily achieved with the new MarSurf WI 50 M, the perfect entry-level solution into the new white light interferometry from Mahr. With an intuitive software user guide and very user-friendly design, this 3D measuring instrument is ideal for everyday use in the laboratory and guality management. Reduced to the essentials, with compact design and large positioning volume: The new WI 50 M meets all the requirements of your measuring tasks in the nanometer range - offering maximum performance and impressive value for money. Adjustment and focusing are simple thanks to the functional tilting table and manual X-, Y- and Z-axes.



White light interferometry | MarSurf WI 50 / WI 100

Flexible all-round measuring solutions whenever and wherever it comes down to the sub-nanometer: This is what the new MarSurf WI 50 and its big brother, the MarSurf WI 100, represent. The high-precision measuring tools for research and quality assurance deliver reliable 3D measuring values – quickly and easily in just a few steps. With its user-friendly design and high measuring speed at full resolution, the instruments reliably record the roughness, even on very smooth surfaces. Due to its HD stitching function, the MarSurf WI 50 and MarSurf WI 100 boast consistently high resolution, even on large measuring surfaces. The integrated collision detection offers users a high level of safety in all directions – both for the workpiece and the instrument itself.

## MarSurf WI 50

- High measuring speed even at full resolution
- CNC functionality in all axes
- Safety through collision detection in all directions to protect the workpiece and measuring system
- HD stitching consistently high resolution, even on large measuring surfaces
- HDR function, 16 bit



## MarSurf WI 100 Automatable measuring system

The high-end MarSurf WI 100 instrument features an extended working area in XYZ direction for especially large sample volumes: Simply use the side adjustment used to move the additional manual Z-axis and measure the XXL components. With its special automation software, the WI 100 can also process user-independent and fully automated series measurements.

- O High measuring speed even at full resolution
- Safety through collision detection in all directions to protect the workpiece and measuring system
- HD stitching consistently high resolution, even on large measuring surfaces
- O CNC functionality in all axes
- User-independent serial measurements by automation software
- Extendable working area in XYZ direction, up to 160 mm in Z-direction

Mahr

Table load bearing capacity of 15 kg

## MarSurf WI 100

32

Mahr

## MarSurf WI 50M

**Dimensions in mm** 

520 x 650 x 760 (L x W x H)



| Measuring head  |  |                                |               |               |
|---|--|--------------------------------|---------------|---------------|
|   | Number of pixels   |                                | 1440 x 1200   | 2448 x 2048   |
| Image capturing   | max. number of measuring points<br>in a single measurement x • y |                                | 1.728 million | 5.013 million |
| module  | Max. image data at full reso                                     | olution                        | 140 Hz        | 35 (70¹) Hz   |
|   | HDR function (16 bit)  |                                | standard      | standard      |
| Maximum number of measuring points <sup>2</sup> (million) |  |                                | 500           | 500           |
| Vertical measuring module                                 | Manual adjustment unit   |                                | 220 mm        | 220 mm        |
|   | Motorized adjuster unit  | Path length measuring system   | -             | -             |
|   |  | vertical adjustment range (mm) | -             | -             |
|   | Fine adjuster<br>(Piezoelectric module)                          | Vertical adjustment range      | 250 µm        | 250 μm        |
| Collision detection x,y                                   | ,Z   |                                | -             | -             |
| Objective helder  | 4x revolver  |                                | -             | -             |
| objective holder  | without revolver   |                                | standard      | standard      |

2. Maximum number of measuring points that can be recorded in a composite measurement. Option to add more.

| Configuration                    |                    |
|----------------------------------|--------------------|
| Tripod form                      | L                  |
| Design of the axes               | manual             |
| Mass                             | 55 kg              |
| Positioning volume x • y • z     | 200 x 105 x 220 mm |
| Path length measuring system x,y | -                  |
| System controller                | integrated         |
| Active vibration dampening       | optional           |

| Software packages |          |
|-------------------|----------|
| MarSurf MSW       | standard |
| MarSurf ASW       | -        |
| MarSurf MfM       | optional |

#### **Export formats**

FITS, NMS, OMS, X3P, ASCII, SDF, SUR, TIF, BMP, STL

#### SMarSurf MSW language packages

German, English, French, Italian, Spanish, Portuguese, Polish, Russian, Turkish, Japanese, Korean, Chinese

#### Sample properties

| · · · ·             |   |
|---------------------|---|
| Max. sample height  | 220 mm  |
| Sample weight, max. | 10 kg   |
| Sample surface      | Reflectivity: 0.1 – 100%,<br>coated, uncoated, reflective to<br>diffuse |

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## MarSurf WI 50

**Dimensions in mm** 383 x 290 x 690 (L x W x H)

Mahr .



| Measuring head                                  |  |                              |               |               |
|---|--|------------------------------|---------------|---------------|
|   | Number of pixels   |                              | 1440 x 1200   | 2448 x 2048   |
| Image capturing                                 | max. number of measuring points<br>in a single measurement x • y |                              | 1.728 million | 5.013 million |
| module  | Max. image data at full resolution                               |                              | 140 Hz        | 35 (70¹) Hz   |
|   | HDR function (16 bit)  |                              | standard      | standard      |
| Maximum number of measuring points <sup>2</sup> |  |                              | 500 million   | 500 million   |
| Vertical measuring module                       | Manual adjustment unit (mm)                                      |                              | -             | -             |
|   | Motorized<br>adjuster unit                                       | Path length measuring system | standard      | standard      |
|   |  | Vertical adjustment range    | 70 mm         | 70 mm         |
|   | Fine adjuster<br>(Piezoelectric module)                          | Vertical adjustment range    | 250 µm        | 250 μm        |
| Collision detection x,y,z                       |  | standard                     | standard      |               |
| Objective holder                                | 4x revolver  |                              | standard      | standard      |
|   | without revolver   |                              | _             | _             |

2. Maximum number of measuring points that can be recorded in a composite measurement. Option to add more.

| Configuration                    |                 |
|----------------------------------|-----------------|
| Tripod form                      | L               |
| Design of the axes               | motorized       |
| Mass                             | 25 kg           |
| Positioning volume x • y • z     | 50 × 50 × 70 mm |
| Path length measuring system x,y | standard        |
| System controller                | integrated      |
| Active vibration dampening       | optional        |

| Software packages |          |
|-------------------|----------|
| MarSurf MSW       | standard |
| MarSurf ASW       | optional |
| MarSurf MfM       | optional |

#### Export formats

FITS, NMS, OMS, X3P, ASCII, SDF, SUR, TIF, BMP, STL

#### MarSurf MSW language packages

German, English, French, Italian, Spanish, Portuguese, Polish, Russian, Turkish, Japanese, Korean, Chinese

| Sample properties |
|-------------------|
|                   |

| <u> </u>            |   |
|---------------------|---|
| Max. sample height  | 70 / (optional 110) mm  |
| Sample weight, max. | 10 kg   |
| Sample surface      | Reflectivity: 0.1 – 100%,<br>coated, uncoated, reflective to<br>diffuse |

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## MarSurf WI 100

**Dimensions in mm** 526 x 378 x 799 (L x W x H)

MarSurf WI 100

48 Optical surface metrology

| Measuring head                                  |  |                              |               |               |
|---|--|------------------------------|---------------|---------------|
|   | Number of pixels   |                              | 1440 x 1200   | 2448 x 2048   |
| Image capturing                                 | max. number of measuring points<br>in a single measurement x • y |                              | 1,728 million | 5,013 million |
| module  | Max. image data at full resolution                               |                              | 140 Hz        | 35 (70¹) Hz   |
|   | HDR function (16 bit)  |                              | standard      | standard      |
| Maximum number of measuring points <sup>2</sup> |  |                              | 500 million   | 500 million   |
| Vertical measuring module                       | Manual adjustment unit (mm)                                      |                              | -             | -             |
|   | Motorized adjuster unit  | Path length measuring system | standard      | standard      |
|   |  | Vertical adjustment range    | 100 mm        | 100 mm        |
|   | Fine adjuster<br>(Piezoelectric module)                          | Vertical adjustment range    | 250 µm        | 250 μm        |
| Collision detection x,y                         | ,Z   |                              | standard      | standard      |
| Objective helder                                | 4x revolver  |                              | standard      | standard      |
| objective holder                                | without revolver   |                              | -             | -             |

2. Maximum number of measuring points that can be recorded

| Configuration                    |                    |
|----------------------------------|--------------------|
| Tripod form                      | L                  |
| Design of the axes               | motorisch          |
| Mass                             | 50 kg              |
| Positioning volume x • y • z     | 100 x 100 x 701 mm |
| Path length measuring system x,y | standard           |
| System controller                | integrated         |
| Active vibration dampening       | optional           |

| Software packages |          |
|-------------------|----------|
| MarSurf MSW       | standard |
| MarSurf ASW       | optional |
| MarSurf MfM       | optional |
|                   | ·        |

#### Export formats

FITS, NMS, OMS, X3P, ASCII, SDF, SUR, TIF, BMP, STL

#### MarSurf MSW language packages

German, English, French, Italian, Spanish, Portuguese, Polish, Russian, Turkish, Japanese, Korean, Chinese

1 Can be expanded to 150 mm with integrated, manual Z-axis

#### Sample properties

| Max. sample height  | 160 mm  |
|---------------------|---|
| Sample weight, max. | 15 kg   |
| Sample surface      | Reflectivity: 0.1 – 100%,<br>coated, uncoated, reflective to<br>diffuse |

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## Technical data General information

| General information    |  |
|------------------------|--|
| Measuring principle    | White light interferometry   |
| Light source           | High-power LED (650 nm), MTBF: 50,000 hours (high-performance white light LED) |
| Typical measuring time | 2-8 s  |
| Electrical power       | Voltage: 100-240 V; frequency: 50-60 Hz, power consumption: approx. 90 W       |

| Objectives   |                              | 2,5x            | 5x             |  |
|--|------------------------------|-----------------|----------------|--|
| Objective lens magnification                                   |                              | 2.5 ×           | 5 ×            |  |
| Lateral measuring range x,y                                    |                              | 7200 x 6000 μm  | 3600 x 3000 μm |  |
| Lateral measuring range x • y                                  |                              | 43.2 mm²        | 10.8 mm²       |  |
| Extended lateral measuring range                               | х,у                          | 139.7 x 97.0 mm | 69.9 x 48.5 mm |  |
| (stitching without data reduction) <sup>1</sup>                | х•у                          | 13,553.5 mm²    | 3,388.4 mm²    |  |
| Numerical aperture NA  |                              | 0.075           | 0.13           |  |
| Working distance   |                              | 10.3 mm         | 9.3 mm         |  |
| Computational critical angle <sup>2</sup>                      |                              | 4.3 °           | 7.5 °          |  |
| Vertical measuring range                                       | with motorized adjuster unit | 9 mm            | 8 mm           |  |
|  | with fine adjuster           | 0.24 mm         | 0.24 mm        |  |
| Macouring poisoo3  | STR⁴                         | 0.14 nm         | 0.14 nm        |  |
| measuring noises*  | ISO 25178-604                | 0.28 nm         | 0.28 nm        |  |
| Vertical recelution 5  | STR                          | 0.4 nm          | 0.4 nm         |  |
| vertical resolution  | ISO 25178-604                | 0.8 nm          | 0.8 nm         |  |
| Compling rate  | 2 MP camera                  | 5 µm            | 2.5 µm         |  |
| Sampling rate  | 5 MP camera                  | 2.93 µm         | 1.46 µm        |  |
| Computational lateral optical critical resolution <sup>6</sup> |                              | 5.04 µm         | 2.91 µm        |  |

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|                         | Standard                | Uncertainty, standard deviation  |
|-------------------------|-------------------------|--|
| with objective lens 20x | Level = 75 µm           | U = 0.200 μm, σ = 0.0400 μm  |
|                         | Level = 10 µm           | U = 0.035 μm, σ = 0.0050 μm  |
|                         | Level = 1 µm            | U = 0.010 μm, σ = 0.0010 μm  |
|                         | Level = 20 nm           | U = 0.005 μm, σ = 0.0002 μm  |
| ·                       | with objective lens 20x | with objective lens 20x $\frac{2000 \text{ Standard}}{2000 \text{ Level} = 75 \ \mu\text{m}}}$ $\frac{2000 \text{ Level} = 10 \ \mu\text{m}}{2000 \text{ Level} = 1 \ \mu\text{m}}}$ $\frac{2000 \text{ Level} = 20 \ \text{nm}}{2000 \text{ Level} = 20 \ \text{nm}}$ |

1. VIM 2012

2. with image capturing module 2448 x 2048 and fine adjuster

3. U as per ISO/IEC GUIDE 98-3:2008(E), GUM:1995, K=1.96

4.  $\sigma$  determined for 25 measurements

5. measured under the best possible conditions using PTB-certified standards. Results only valid for used standards.

6. Evaluation according to ISO 4287

| 10x            | 20x            | 50x          | 100x         |
|----------------|----------------|--------------|--------------|
| 10 ×           | 20 ×           | 50 ×         | 100 ×        |
| 1800 x 1500 μm | 900 x 750 μm   | 360 x 300 μm | 180 x 150 μm |
| 2.7 mm²        | 0.675 mm²      | 0.108 mm²    | 0.027 mm²    |
| 34.9 x 24.3 mm | 17.5 x 12.1 mm | 7.0 x 4.9 mm | 3.5 x 2.4 mm |
| 847.1 mm²      | 211.8 mm²      | 33.9 mm²     | 8.5 mm²      |
| 0.3            | 0.4            | 0.55         | 0.7          |
| 7.4 mm         | 4.7 mm         | 3.4 mm       | 2 mm         |
| 17.5 °         | 23.6 °         | 33.4 °       | 44.4 °       |
| 7 mm           | 4.2 mm         | 3 mm         | 1.6 mm       |
| 0.24 mm        | 0.24 mm        | 0.24 mm      | 0.24 mm      |
| 0.08 nm        | 0.08 nm        | 0.08 nm      | 0.08 nm      |
| 0.16 nm        | 0.16 nm        | 0.16 nm      | 0.16 nm      |
| 0.2 nm         | 0.2 nm         | 0.2 nm       | 0.2 nm       |
| 0.43 nm        | 0.43 nm        | 0.43 nm      | 0.43 nm      |
| 1.25 µm        | 0.62 µm        | 0.25 μm      | 0.13 µm      |
| 0.73 μm        | 0.37 µm        | 0.15 µm      | 0.07 µm      |
| 1.26 µm        | 0.95 µm        | 0.69 µm      | 0.54 µm      |

1. Based on example of image capturing module 2 MP at full resolution

2. theoretical critical angles on reflective surfaces, on real surfaces can achieve larger critical angles due to diffuse reflections.

4. Individual measurement with 3 x 3 median filter

5. specified according to "Fair Data Sheet" (measuring noises \* 2.83)

6. 620 nm light source, calculated according to the Rayleigh criterion

3. with fine adjuster

# 1600 S 10×/0,3/0000-11





Confocal technology | MarSurf CM

## One technology, many advantages

Optical 3D microscopy stands for maximum performance by combining a high measuring point density with measurements that are completed in seconds. The latest image sensors, high performance optics, and precise path length measurement systems provide accurate results. In short, technology you can rely on.

# **Highest signal quality** thanks to multi-pinhole technology

The high-performance confocal microscopes from the MarSurf product range record images extremely quickly thanks to the patented multi-pinhole technology developed by Mahr. It represents an even stochastic distribution, as adjacent measuring points are not measured immediately after one another. Confocal microscopes from Mahr also stand out for generating an extremely low amount of scattered light and strong signals, while providing a high light output. The microscopes can thus achieve height resolutions into the nanometer range.



CCF MAX Highest correlation to tactile measuring data

50,000 MTBF

#### MPD technology

Artifact-free, fast, lowest noise level, no preferred direction

#### TrueDetection technology

100x measuring point sampling, extremely stable measuring data/repeatability

#### Piezo drive

for maximum vertical resolution

#### Objectives

Largest, square measuring fields, for roughness measurement in a measuring field/best homogeneous illumination





## Mobile 3D surface measurement

Regardless of whether the surface is sensitive, very large, or even shiny: The MarSurf CM *mobile* combines the unique properties of a portable and robust measuring system for production with the established functionality of a stationary system. The MarSurf CM *mobile* provides reliable and accurate measurements. Thanks to confocal 3D metrology, your measurements are quick, contactless and material-independent.

In particular for measurements on large objects and specimens that are difficult to move, such as rollers and car bodies, the MarSurf CM *mobile* will impress you with its compact size, giving you the option to stitch larger measuring fields at a consistently high resolution thanks to the motorized axes. Featuring a lens revolver, the option of a color camera and application-specific software solutions, the measuring system fulfills the requirements of a wide range of measuring tasks and can be used wherever your work requires it.



#### HD stitching

High resolution, even with large measuring surfaces, due to motorized axes

#### Versatile

Roughness and microgeometrical measurements in one system



#### Get to know the entire MarSurf CM portfolio!

Do you require a stationary measuring station or want an automated solution? Visit our website!



Reliable results, even in the production environment

1200 × 1200 Camera resolution

1.4 million

Measuring points per individual measurement

0.13 µm Minimum measuring point level

100 fps even at maximum resolution

5 Bit High dynamic range camera



**Unique specifications** 

Roughness measurements as per ISO 4287, ISO 21920, and ISO 25178

## **Quality manager** for all heights and depths

The high-performance MarSurf CM devices provide a reliable measurement on all surfaces, regardless of the surface quality, and a high level of flank acceptability and dynamics. The devices offer users an excellent resolution and the most robust design. In addition, the state-of-the-art tools provide ultrafast measurements with a large measuring point density, that provide high-quality and unfiltered raw data. The patented multi-pinhole disc ensures that the process emits a particularly low amount of scattered light.

### MarSurf CM explorer

The flexible, versatilemeasuring solution

The MarSurf CM explorer is a compact and user-friendly complete package for the accurate measurement and analysis of surfaces. The measuring system is fully equipped with the HDR function, automatic objective lens recognition, and collision detection in all spatial directions. It stands out for its cost-effective use in laboratories, as well as assuring the quality in production settings.

- High measuring speed even at full resolution
- User-friendly concept
- Safe thanks to collision detection
- HDR function 16 bit
- HD stitching consistently high resolution, even on large measuring surfaces



### MarSurf CM *expert* The high-performance laboratory measuring system

The MarSurf CM *expert* offers user-independent and fully automatic measurements making it ideal for straightforward quality assurance applications. The measuring system provides a traverse path of 100 x 100 mm<sup>2</sup> and additional manual Z positioning for large sample volumes.

- O Can be automated
- O Max. sample volumes even of heavy components
- O High measuring speed even at full resolution
- O Safe due to collision detection
- O HDR function, 16 bit
- HD stitching consistently high resolution, even on large measuring surfaces

Mahr

MarSurf CM expert

O User-friendly concept

Mahr

Ó

## Modular multisensor system

Thanks to its modular design, the MarSurf CM *select* can be assembled to meet your specific requirements and can be adjusted to your measuring tasks with regard to automation, measuring convenience, and accuracy requirements. A large selection of hardware and software components are available for individually tailored solutions.

The MarSurf CM *select* is thus the perfect solution for automated quality assurance processes and a variety of applications in research laboratories and production environments. As a multisensor system, the MarSurf CM *select* offers the possibility of combining different sensor technologies in one measuring device. Depending on the measuring task, users can flexibly select the optimal sensor. Practical and easy to use: The software controls all of the standard sensors.

### MarSurf CM select

- Can be configured individually
- Fully automated
- Large traverse units
- Production-related interface
- Safe thanks to collision detection
- Designed for continuous operation

# Offset camera To easily set measurements and detect registration marks

Measuring speed

Combined in one system

and precision

#### Multisensor head

Confocal surface sensor, profilometer module available as option

Mahr



60 | Optical surface metrology

Complete profilometer can be integrated as an option



MarSurf CM select



X/Y-axes path length measuring system

Available in different sizes

#### Subframes

With active/passive vibration isolation for all ambient conditions

0,1-100 Reflectivity of all the sample surfaces

Mahr



Highest correlation to tactile measuring data

4000 Hz

Maximum measuring frequency

MarSurf CM | Device information



**Dimensions in mm** 417 × 136 × 234



| Measuring head                                  |   |                              |                            |
|---|---|------------------------------|----------------------------|
|   | max. number of measuring points in a single measurement x • y |                              | 1200 × 1200 = 1.44 million |
|   | max. image data at full resolution <sup>1</sup>               |                              | 25/(100) Hz                |
| image capturing module                          | HDR function (16 bit)   |                              | standard                   |
|   | Color photo   |                              | optional                   |
| Maximum number of measuring points <sup>2</sup> |   |                              | 1213 million               |
|   | motorized adjuster unit                                       | Path length measuring system | -                          |
| rr<br>Vertical measuring<br>module<br>F<br>(F   |   | vertical adjustment range    | 35 mm                      |
|   | Fine adjuster<br>(Piezoelectric module)                       | vertical adjustment range    | 350 μm                     |
| Collision detection x,y,z                       |   |                              | -                          |
|   | 4x revolver   |                              | standard                   |
| Objective lens holder                           | motorized revolver  |                              | -                          |
|   | without revolver  |                              | optional                   |
|   |   |                              |                            |

2. Maximum number of measuring points that can be recorded in a composite measurement.

| Configuration                    |                 |
|----------------------------------|-----------------|
| Tripod form                      | mobile          |
| Mass                             | 8.3 kg          |
| Positioning volume x • y • z     | 50 × 50 × 35 mm |
| Path length measuring system x,y | standard        |
| System controller                | integrated      |
| Passive vibration dampening      | optional        |
| Active vibration dampening       | optional        |

| Software packages |          |
|-------------------|----------|
| MarSurf MSW       | standard |
| MarSurf ASW       | -        |
| MarSurf MfM       | optional |

#### Export formats

FITS, NMS, OMS, X3P, ASCII, SDF, SUR, TIF, BMP, STL

#### MarSurf MSW language packs

German, English, French, Italian, Spanish, Portuguese, Polish, Russian, Turkish, Japanese, Korean, Chinese

1. Can be expanded to 150 mm with integrated, manual Z-axis

| Sample properties       |   |
|-------------------------|---|
| Sample height (mm)      | flexible  |
| Sample weight max. (kg) | flexible  |
| Sample surface          | Reflectivity: 0.1 – 100%,<br>coated, uncoated,<br>reflective to diffuse |



| Measuring head        |   |   |                              |                            |
|-----------------------|---|---|------------------------------|----------------------------|
|                       |   | max. number of measuring points in a single measurement $x\boldsymbol{\cdot} y$ |                              | 1200 × 1200 = 1.44 million |
|                       | onturing modulo                         | max. image data at full resolution <sup>1</sup>                                 |                              | 25/(100) Hz                |
| inage c               | apturing module                         | HDR function (16 bit)   |                              | standard                   |
|                       |   | Color photo   |                              | optional                   |
| Maximu                | ım number of mea                        | suring points <sup>2</sup>  |                              | 1213 million               |
|                       |   | motorized adjuster unit   | Path length measuring system | standard                   |
| Vertical              | Vertical measuring                      |   | vertical adjustment range    | 70 mm                      |
| module                | Fine adjuster<br>(Piezoelectric module) | vertical adjustment range   | 350 µm                       |                            |
| Collisior             | n detection x,y,z                       |   |                              | standard                   |
| Objective lens holder |   | 4x revolver   |                              | standard                   |
|                       |   | motorized revolver  |                              | optional                   |
|                       |   | without revolver  |                              | _                          |
|                       |   |   |                              |                            |

2. Maximum number of measuring points that can be recorded in a composite measurement.

| Configuration                    |                 |
|----------------------------------|-----------------|
| Tripod form                      | L               |
| Mass                             | 25 kg           |
| Positioning volume x • y • z     | 50 × 50 × 70 mm |
| Path length measuring system x,y | standard        |
| System controller                | integrated      |
| Passive vibration dampening      | integrated      |
| Active vibration dampening       | optional        |

| Software packages |          |
|-------------------|----------|
| MarSurf MSW       | standard |
| MarSurf ASW       | -        |
| MarSurf MfM       | optional |

#### Export formats

FITS, NMS, OMS, X3P, ASCII, SDF, SUR, TIF, BMP, STL

#### MarSurf MSW language packs

German, English, French, Italian, Spanish, Portuguese, Polish, Russian, Turkish, Japanese, Korean, Chinese

1. Can be expanded to 150 mm with integrated, manual Z-axis

| Sample properties   |   |
|---------------------|---|
| Sample height       | 70 / (optional 110) mm  |
| Sample weight, max. | 10 kg   |
| Sample surface      | Reflectivity: 0.1 – 100%,<br>coated, uncoated,<br>reflective to diffuse |



| Measuring head                                  |   |                              |                            |
|---|---|------------------------------|----------------------------|
|   | max. number of measuring points in a single measurement $x \cdot y$ |                              | 1200 × 1200 = 1.44 million |
|   | max. image data at full resolution <sup>1</sup>                     |                              | 25/(100) Hz                |
| image capturing module                          | HDR function (16 bit)   |                              | standard                   |
|   | Color photo   |                              | optional                   |
| Maximum number of measuring points <sup>2</sup> |   | 1213 million                 |                            |
|   | motorized adjuster unit   | Path length measuring system | standard                   |
| Vertical measuring<br>module                    |   | vertical adjustment range    | 70 mm                      |
|   | Fine adjuster<br>(Piezoelectric module)                             | vertical adjustment range    | 350 µm                     |
| Collision detection x,y,z                       |   |                              | standard                   |
|   | 4x revolver   |                              | standard                   |
| Objective lens holder                           | motorized revolver  |                              | optional                   |
|   | without revolver  |                              | optional                   |
|   |   |                              |                            |

2. Maximum number of measuring points that can be recorded in a composite measurement.

| Configuration                    |                   |
|----------------------------------|-------------------|
| Tripod form                      | L                 |
| Mass                             | 48 kg             |
| Positioning volume x • y • z     | 100 × 100 × 70 mm |
| Path length measuring system x,y | standard          |
| System controller                | integrated        |
| Passive vibration dampening      | integrated        |
| Active vibration dampening       | optional          |

| Software packages |          |
|-------------------|----------|
| MarSurf MSW       | standard |
| MarSurf ASW       | optional |
| MarSurf MfM       | optional |

#### Export formats

FITS, NMS, OMS, X3P, ASCII, SDF, SUR, TIF, BMP, STL

#### MarSurf MSW language packs

German, English, French, Italian, Spanish, Portuguese, Polish, Russian, Turkish, Japanese, Korean, Chinese

1. Can be expanded to 150 mm with integrated, manual Z-axis

| Sample properties   |   |
|---------------------|---|
| Sample height       | 160 / (optional 180) mm   |
| Sample weight, max. | 10 kg   |
| Sample surface      | Reflectivity: 0.1 – 100%,<br>coated, uncoated,<br>reflective to diffuse |

## MarSurf CM select

Dimensions in mm

900 x 750 x 1.614 (portal)



|   | Measuring head                          |                                    |                              |             |
|---|---|------------------------------------|------------------------------|-------------|
| max. number of measuring points in a single measurement x •<br> |   | ints in a single measurement x • y | 1200 x 1200 = 1.44 million   |             |
|   |   | max. image data at full resolut    | tion <sup>1</sup>            | 100/(25) Hz |
|   | inage capturing module                  | HDR function (16 bit)              |                              | standard    |
|   |   | Color photo                        |                              | optional    |
| Maximum number of measuring points <sup>2</sup>                 |   |                                    | 1213 million                 |             |
|   |   |                                    | Path length measuring system | optional    |
| Vertical measuring<br>module                                    | motorized adjuster unit                 | vertical adjustment range          | 100 mm                       |             |
|   | Fine adjuster<br>(Piezoelectric module) | vertical adjustment range          | 350 μm                       |             |
|   | Collision detection x,y,z               |                                    |                              | optional    |
|   |   | 4x revolver                        |                              | optional    |
| Objective lens holder   |   | motorized revolver                 |                              | optional    |
|   |   | without revolver                   |                              | standard    |
| 1   |   |                                    |                              |             |

2. Maximum number of measuring points that can be recorded in a composite measurement.

| Configuration                    |                    |  |
|----------------------------------|--------------------|--|
| Tripod form                      | Portal             |  |
| Mass                             | ~ 300 kg           |  |
|                                  | 200 x 200 × 100 mm |  |
|                                  | 300 × 300 × 100 mm |  |
| Path length measuring system x,y | optional           |  |
| System controller                | Roller container   |  |
| Passive vibration dampening      | standard           |  |
| Active vibration dampening       | optional           |  |

| standard |
|----------|
| optional |
| optional |
|          |

#### Export formats

FITS, NMS, OMS, X3P, ASCII, SDF, SUR, TIF, BMP, STL

#### MarSurf MSW language packs

German, English, French, Italian, Spanish, Portuguese, Polish, Russian, Turkish, Japanese, Korean, Chinese

1. Can be expanded to 150 mm with integrated, manual Z-axis

#### Sample properties

| entre brebernes         |   |
|-------------------------|---|
| Sample height (mm)      | on request  |
| Sample weight max. (kg) | 15 / on request   |
| Sample surface          | Reflectivity: 0.1 – 100%,<br>coated, uncoated,<br>reflective to diffuse |

Point sensors

Refer to specification page for MarSurf CP

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## Technical data General information

| General information        |  |
|----------------------------|--|
| Measuring principle        | Patented CMP technology (confocal multi-pinhole)   |
| Light source               | High-performance LED (505/475 nm), MTBF: 50,000 hours (color camera with high-performance white light LED) |
| Typical measuring time (s) | 2-8  |
| Dimensions                 | See technical drawings on the following pages  |

| Objectives                                      |                              | 3200S                 | 1600S                | 800L                |  |
|---|------------------------------|-----------------------|----------------------|---------------------|--|
| Objective lens magnification                    |                              | 5 ×                   | 10 ×                 | 20 ×                |  |
| Lateral measuring range x,y                     |                              | 3200 µm               | 1600 µm              | 800 µm              |  |
| Lateral measuring range x • y                   |                              | 10.24 mm <sup>2</sup> | 2.56 mm <sup>2</sup> | 0.64 mm²            |  |
| Extended lateral measuring range                | х.у                          | 92.8 mm               | 46.4 mm              | 23.2 mm             |  |
| (stitching without data reduction) <sup>2</sup> | x • y                        | 8611 mm²              | 2152 mm <sup>2</sup> | 538 mm <sup>2</sup> |  |
| Numerical aperture NA                           |                              | 0.15                  | 0.3                  | 0.4                 |  |
| Working distance                                |                              | 20 mm                 | 11 mm                | 12 mm               |  |
| Computational critical angle <sup>3</sup>       |                              | 8.6 °                 | 17.5 °               | 23.6 °              |  |
| Vertical macauring range                        | with motorized adjuster unit | 19.9 mm               | 10.9 mm              | 11.9 mm             |  |
| vertical measuring range                        | with fine adjuster           | 0.35 mm               | 0.35 mm              | 0.35 mm             |  |
| Macouring poiss                                 | with motorized adjuster unit | 354 nm                | 71 nm                | 25 nm               |  |
| Measuring hoise                                 | with fine adjuster           | -                     | 14 nm                | 4 nm                |  |
| Vertical recelution                             | with motorized adjuster unit | 1000 nm               | 200 nm               | 70 nm               |  |
| ventical resolution                             | with fine adjuster           | -                     | 40 nm                | 12 nm               |  |
| Sampling rate                                   | 1200 x 1200 pixels           | 2.67 µm               | 1.33 µm              | 0.67 µm             |  |
| Computational lateral optical critical resol    | lution <sup>4</sup>          | 1.93 µm               | 0.96 µm              | 0.72 µm             |  |

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| Accuracy <sup>1,2</sup>   |                           | Standard      | Uncertainty, standard deviation |
|---|---------------------------|---------------|---------------------------------|
|   | with objective lens 800XS | Level = 75 µm | U = 0.320 μm, σ = 0.050 μm      |
| Measurement uncertainty based on the exam-<br>ple of step height measurement <sup>2,3,4,5,6</sup> |                           | Level = 10 µm | U = 0.060 μm, σ = 0.020 μm      |
|   |                           | Level = 1 µm  | U = 0.030 μm, σ = 0.004 μm      |
|   |                           | Ra = 1.63 µm  | U = 0.040 μm, σ = 0.004 μm      |
| Measurement uncertainty based on the example of roughness measurement <sup>2,3,4,5</sup>          | with objective lens 800XS | Ra = 0.58 µm  | U = 0.024 μm, σ = 0.0066 μm     |
|   |                           | Ra = 0.23 µm  | U = 0.010 μm, σ = 0.0050 μm     |
|   | with objective lens 320S  | Ra = 0.079 µm | U = 0.010 μm, σ = 0.0022 μm     |
|   | with objective lens 160XS | Ra = 0.079 µm | U = 0.003 μm, σ = 0.0004 μm     |

1. VIM 2012

2. with image capturing module 1200x1200 and fine adjuster

S: standard working distance XS: short working distance

L: long working distance

3. U as per ISO/IEC GUIDE 98-3:2008(E), GUM:1995, K=1.96

4.  $\sigma$  determined for 25 measurements

 measured under the best possible conditions using PTB-certified standards. Results only valid for used standards.

6. Evaluation according to ISO 4287

| 800S                 | 800XS                | 320L                   | 320S                 | 320XS1                 | 160L                   | 160S                   | 160XS1                 |
|----------------------|----------------------|------------------------|----------------------|------------------------|------------------------|------------------------|------------------------|
| 20 ×                 | 20 ×                 | 50 ×                   | 50 ×                 | 50 ×                   | 100 ×                  | 100 ×                  | 100 ×                  |
| 800 µm               | 800 µm               | 320 µm                 | 320 µm               | 320 µm                 | 160 µm                 | 160 µm                 | 160 µm                 |
| 0.64 mm <sup>2</sup> | 0.64 mm <sup>2</sup> | 0.1024 mm <sup>2</sup> | 0.1024 mm²           | 0.1024 mm <sup>2</sup> | 0.0256 mm <sup>2</sup> | 0.0256 mm <sup>2</sup> | 0.0256 mm <sup>2</sup> |
| 23.2 mm              | 23.2 mm              | 9.2 mm                 | 9.2 mm               | 9.2 mm                 | 4.6 mm                 | 4.6 mm                 | 4.6 mm                 |
| 538 mm²              | 538 mm²              | 84.6 mm²               | 84.6 mm <sup>2</sup> | 84.6 mm²               | 21.1 mm²               | 21.1 mm²               | 21.1 mm²               |
| 0.45                 | 0.6                  | 0.5                    | 0.8                  | 0.95                   | 0.8                    | 0.9                    | 0.95                   |
| 3.1 mm               | 1 mm                 | 10.6 mm                | 1 mm                 | 0.35 mm                | 3.4 mm                 | 1 mm                   | 0.35 mm                |
| 26.7 °               | 36.9 °               | 30.0 °                 | 53.1 °               | 71.8 °                 | 53.1 °                 | 64.2 °                 | 71.8 °                 |
| 3 mm                 | 0.9 mm               | 10.5 mm                | 0.9 mm               | 0.25 mm                | 3.3 mm                 | 0.9 mm                 | 0.25 mm                |
| 0.35 mm              | 0.35 mm              | 0.35 mm                | 0.35 mm              | 0.34 mm                | 0.35 mm                | 0.35 mm                | 0.34 mm                |
| 25 nm                | 14 nm                | 14 nm                  | 14 nm                | 14 nm                  | 14 nm                  | 14 nm                  | 14 nm                  |
| 4 nm                 | 3 nm                 | 3 nm                   | 1 nm                 | 1 nm                   | 1 nm                   | 1 nm                   | 1 nm                   |
| 70 nm                | 40 nm                | 40 nm                  | 40 nm                | 40 nm                  | 40 nm                  | 40 nm                  | 40 nm                  |
| 10 nm                | 8 nm                 | 8 nm                   | 4 nm                 | 4 nm                   | 4 nm                   | 2 nm                   | 2 nm                   |
| 0.67 µm              | 0.67 µm              | 0.27 µm                | 0.27 µm              | 0.27 µm                | 0.13 µm                | 0.13 µm                | 0.13 µm                |
| 0.64 µm              | 0.48 µm              | 0.58 µm                | 0.36 µm              | 0.30 µm                | 0.36 µm                | 0.32 µm                | 0.30 µm                |

1. not with MarSurf CM mobile

2. Based on example of image capturing module 1200 x 1200 at full resolution

3. theoretical critical angles on reflective surfaces, on real surfaces can achieve larger critical angles due to diffuse reflections.

4. Example of a 475 nm light source, calculated according to the Rayleigh criterion


MarSurf | Optical 3D profilometry

# High flexibility and **individual configuration**

The high-performance profilometer platform from Mahr, the MarSurf CP *select* and MarSurf CL select supplies users with accurate information about surface structures and production processes. Measuring processes and data analyses are fully automated and completed without intermediate steps, that take up a lot of time, thus guaranteeing maximum reproducibility. Their stable, mechanical design ensures that the tools minimize all environmental influences.

# Flexible 3D profilometer for quality control

The MarSurf CP *select* 3D profilometer has proven itself many times over when measuring topography, line roughness, height profiles, or layer thickness during the production process. Its modular design and ability to combine with different sensors mean that it can adapt to many different measuring tasks. The manual Z-adjuster with fine adjustment guarantees extreme ease of use. Alternatively, there is also a motorized Z-axis. The setup on granite and the use of top-quality components guarantee high repeatability of measurements. In addition, it is also possible to measure large and heavy samples effortlessly.

#### **Point sensors**



mm/s

Maximum measuring speed nm

Vertical optical

resolution





5 Sec Typical measuring time for 2D roughness measurements 70 mm WD Maximum working distance to the probe



# **Ultrafast linear sensor** for large scale 3D measurement

The MarSurf CL select stands out for extremely fast, three dimensional recording of large measuring surfaces while also ensuring high measuring precision. The system does not just record one profile, but 192 profile lines in parallel. Topographies can thus be recorded in just a few seconds from the  $\mu$ m to the cm range. High measuring speed ensures that high throughput rates are achieved. This will save you a significant amount of time compared to classic profilometers.

Profile data on practically all surfaces with a variety of reflective properties and inclinations are recorded extremely accurately thanks to the high level of dynamics. The setup on granite and the use of top-quality components guarantee high repeatability of measurements. It is also possible to measure large and heavy samples effortlessly.

## MarSurf CL select

- Large scale 3D measurements
- Very high measuring speed
- Excellent dynamics and precision
- Layer thickness measurement and measurement of transparent materials
- Can be automated

#### Non-contact and non-destructive measurement

Profile data on practically all surfaces are recorded extremely accurately due to the high level of dynamics.

# Adaptation to different measuring tasks

Thanks to modular design and Different sensors can be combined

#### Measuring range expansion

Large scale 3D measurements



100 mm/s Maximum measuring speed 20 nm Maximum measuring speed



Available soon 1200 Profiles 11.9 Max. line width Max. data rate 9,000,000 Measuring points/ second

**Complex surfaces** 

Non-contact and non-destructive layer thickness measurement and measurement of transparent materials

192 Profiles Parallel profile lines with linear sensor







# **MarSurf** optical 3D profilometry

| Туре                                   | Name   | Measuring<br>range   | Working<br>distance  | Measuring spot<br>diameter   | Lateral resolution  |
|--|--|--|--|--|---|
|  | CP 0.6   | 0.6 mm   | 6.5 mm   | 4 µm   | 2 µm  |
| -                                      | CP 1   | 1 mm   | 19.1 mm  | 3.5 µm   | 1.8 µm  |
| Chromatic<br>sensors CP <sup>3,4</sup> | CP 3   | 3 mm   | 22.5 mm  | 12 µm  | 6 µm  |
|  | CP 6   | 6 mm   | 35 mm  | 16 µm  | 8 µm  |
|  | CP 10  | 10 mm  | 70 mm  | 24 µm  | 12 µm   |
|  | CPC 0.6  | 0.6 mm   | 6.5 mm   | 6 µm   | 3 µm  |
| Chromatic<br>sensors CPC               | CPC 4  | 4 mm   | 37.5 mm  | 16 µm  | 8 µm  |
|  | CPC 10   | 1 mm   | 69 mm  | 32 µm  | 16 µm   |
|  | Type<br>Chromatic<br>sensors CP <sup>3,4</sup> | TypeNameCP 0.6CP 1CP 1CP 3CP 3CP 6CP 10CP 10CPC 0.6CPC 4CPC 10 | TypeNameMeasuring<br>rangeCP 0.60.6 mmCP 0.60.6 mmCP 11 mmCP 33 mmCP 66 mmCP 1010 mmCP 1010 mmCPC 0.60.6 mmCPC 0.60.6 mmCPC 101 mm | Type Name Measuring<br>range Working<br>distance   CP 0.6 0.6 mm 6.5 mm   CP 1 1 mm 19.1 mm   CP 3 3 mm 22.5 mm   CP 6 6 mm 35 mm   CP 10 10 mm 70 mm   CP 10 10 mm 70 mm   CP 0.6 0.6 mm 6.5 mm | Type Name Measuring<br>range Working<br>distance Measuring spot<br>diameter   CP 0.6 0.6 mm 6.5 mm 4 μm   CP 1 1 mm 19.1 mm 3.5 μm   CP 3 3 mm 22.5 mm 12 μm   CP 6 6 mm 35 mm 16 μm   CP 10 10 mm 70 mm 24 μm   CP 0.6 0.6 mm 6.5 mm 6 μm   CP 10 10 mm 70 mm 24 μm   CPC 0.6 0.6 mm 6.5 mm 6 μm   CPC 0.6 0.6 mm 6.5 mm 32 μm |

1. Larger probe arm angles possible for dispersed surfaces

3. Other sensors available on request

4. Two sensors can be integrated in one holder

| Sensors                  |                                      |        |                    |                |                     |                            |  |
|--------------------------|--------------------------------------|--------|--------------------|----------------|---------------------|----------------------------|--|
|                          | Туре                                 | Name   | Measuring<br>range | Line length    | Working<br>distance | Measuring spot<br>diameter |  |
| Line<br>sensors Ch<br>se | Chromatic<br>sensors CL <sup>3</sup> | CL 0.2 | 0.2 mm             | 0.96 ± 0.01 mm | 5.3 ± 0.2 mm        | 2 µm                       |  |
|                          |                                      | CL 1   | 0.95 mm            | 1.91 ± 0.01 mm | 18.5 ± 0.2 mm       | 4 µm                       |  |
|                          |                                      | CL 4   | 3.9 mm             | 4.78 ± 0.02 mm | 41 ± 0.2 mm         | 10 µm                      |  |

1. Larger probe arm angles possible for dispersed surfaces

2. Refractive index = 1.5

2. Refractive index = 1.5

3. Other sensors available on request

| Camera                          |                                |                  |                  | Vertical adjustment |           |                   |
|---------------------------------|--------------------------------|------------------|------------------|---------------------|-----------|-------------------|
| Overview                        | Overview Color off axis-camera |                  |                  |                     | Manuali   | Displacement path |
| camera                          | Monitoring area                | up to 10 x 10 mm |                  | A                   | Manual    | Fine adjustment   |
|                                 | External bright field/dark     | optional         | Adjusting unit 2 |                     | Motorized | Displacement path |
| field illumination <sup>1</sup> |                                |                  |                  |                     | wotonzeu  | Resolution z      |

1. Only for MarSurf CL select

1. Only for MarSurf CP select

150 mm

optional 100 mm

0.1 µm

| Vertical resolution | Linearity | Probe arm angle <sup>1</sup> | Thickness measuring<br>range² up to | Max. measuring<br>rate | Light<br>source |
|---------------------|-----------|------------------------------|-------------------------------------|------------------------|-----------------|
| 3 nm                | 0.198 µm  | 90 ± 30 °                    | 0.9 mm                              |                        |                 |
| 4 nm                | 0.33 µm   | 90 ± 45 °                    | 1.5 mm                              |                        |                 |
| 8 nm                | 0.99 µm   | 90 ± 30 °                    | 4.5 mm                              | 4 kHz                  |                 |
| 14 nm               | 2 µm      | 90 ± 25 °                    | 9 mm                                |                        |                 |
| 22 nm               | 3.3 µm    | 90 ± 20 °                    | 15 mm                               |                        | LED             |
| 25 nm               | 0.22 µm   | 90 ± 30 °                    | 0.9 mm                              |                        |                 |
| 18 nm               | 1.4 µm    | 90 ± 20 °                    | 6 mm                                | 2 (4) kHz              |                 |
| 400 nm              | 4 µm      | 90 ± 14 °                    | 15 mm                               |                        |                 |

| Lateral resolution | Vertical resolution | Probe arm angle <sup>1</sup> | Thickness measuring<br>range² up to | Measuring rate | Light<br>source |
|--------------------|---------------------|------------------------------|-------------------------------------|----------------|-----------------|
| <br>1 µm           | 0.020 µm            | 90 ± 44 °                    | 0.28 mm                             |                |                 |
| 2 µm               | 0.080 µm            | 90 ± 33 °                    | 1.35 mm                             | 2 kHz          | LED             |
| 5 µm               | 0.320 µm            | 90 ± 20 °                    | 5.5 mm                              |                |                 |

# **MarSurf** optical 3D profilometry



| Scan module                   |                                   |              |              |              |                        |                        |
|-------------------------------|-----------------------------------|--------------|--------------|--------------|------------------------|------------------------|
| Portal                        |                                   | S            | М            | L            | XL                     | XXL+                   |
| Axis system                   | Measuring range                   | 100 x 150 mm | 200 x 200 mm | 200 x 300 mm | 200 x 300 mm           | 300 x 300 mm           |
| x/y                           | Resolution x/y                    | 0.5 µm       | 0.5 µm       | 0.5 µm       | 0.5 µm                 | 0.05 µm                |
| System                        | Standing container                | standard     | standard     | standard     | -                      | -                      |
| controller                    | Roller container                  | optional     | optional     | optional     | standard               | standard               |
| Subframe wi<br>active vibrati | th passive/<br>on damping         | _            | -            | -            | standard /<br>optional | standard /<br>optional |
| MarSurf CP                    | Portal weight                     | 100 kg       | 130 kg       | 150 kg       | 250 kg                 | 350 kg                 |
|                               | max. sample height                | 125 mm       | 125 mm       | 125 mm       | 125 mm                 | 125 mm                 |
|                               | max. transit width in X-direction | 360 mm       | 500 mm       | 500 mm       | 720 mm                 | 710 mm                 |
|                               | max. sample weight                | 10 kg        | 10 kg        | 10 kg        | 10 kg                  | 50 kg                  |
|                               | max. sample height                | 95 mm        | 95 mm        | 95 mm        | 95 mm                  | 95 mm                  |
| MarSurf CL                    | max. transit width in X-direction | 360 mm       | 500 mm       | 500 mm       | 720 mm                 | 710 mm                 |
|                               | max. sample weight                | 10 kg        | 10 kg        | 10 kg        | 10 kg                  | 50 kg                  |

| General information            |   | Software packages |  |  |  |
|--------------------------------|---|-------------------|--|--|--|
|                                | Voltage: 100-240 V; frequency:                | MarSurf MSW       | including                                      |  |  |
| Power supply                   | 50-60 Hz, power consumption:<br>approx. 550 W | MarSurf ASW       | optional                                       |  |  |
| Type of computer Industrial PC |   | MarSurf MfM       | optional                                       |  |  |
|                                |   | Export formats    | FITS, X3P, NMS, OMS, ASCII, SDF, TIF, BMP, SUR |  |  |



Mahr | Engineered Solutions

# Beyond the standard – your tailor-made measuring station

Measuring solutions that are as individual as your measuring task. With Engineered Solutions, Mahr provides you with solutions that are perfectly tailored to your workpieces. Guaranteed to be tailored to your requirements for the handling, reliability, and speed of your production environment.

# From the special solution to the tried and tested all-rounder

What challenge are you facing? There are many reasons why an individual measuring solution may be required. There is generally a problem that cannot be solved or is very labor-intensive to solve with the usual standard measuring machines. Complex measuring tasks therefore strive for maximum efficiency. In addition, measuring results on site or the desire for maximum ease of use sometimes require solutions that have only been individually designed with these requirements in mind. With Engineered Solutions, Mahr consolidates its extensive product expertise to design tailor-made measuring

#### Typical customer demands we receive

- Measurement directly in production
- Measurements that are easy for on-site personnel to carry out
- Measuring results within a few seconds
- Reliable completion of complex and demanding measuring tasks
- Simplification of measuring tasks that occur on a daily basis
- 100% inline control solutions for integration in the production line
- Measuring results that can be documented and traced



Dimensional metrology



Surface and contour measurement



Automation



Accessories



You benefit from only requiring minimal space despite integrated special solutions and a personalized assembly.

One of our special solutions is now very well established: the Mahr five-axis system with integrated turning/swivel unit. It can be used to complete measurements on components with complex geometries, such as medical implants or extruded components.



# Solutions can be so different

Do you have particularly large or particularly heavy workpieces, such as crankshaft housings? No worries! Then we will simply adjust the axis systems of your measuring instrument to your requirements. You will thus be able to quickly and easily complete your measuring tasks. We create customer-specific sample holders and recording systems, or provide you with integration interfaces. We will also find the perfect automation solution tailored to your process. Talk to us!

## Multisensor system

- Point/linear sensor
- 3D sensors
- Vision

## Pick-place solutions

- Robot connection
- Palette solution

As a renowned manufacturer of metrology, we offer ideal conditions for joint individual projects with our customers. Indeed, when developing our customized solutions, we draw on a broad portfolio of proven sensor technology and tested technologies. Your needs are our focus – without limitation.

# Mahr worldwide – Our sites

With 20 Mahr locations in America, Asia and Europe and an additional 39 dealerships around the world, we have created a broad network to ensure an international presence on five continents: from South Africa, Brazil, Egypt, Argentina and Vietnam to Greece, Russia, the UK, and Australia.





- 60 Countries

39 Dealerships





Handheld metrology Calipers, micrometers, and dial indicators – analog or digital including integrated wireless transmission



Length metrology Electric measuring probe, pneumatic length measuring systems right through to gages, as well as display and evaluation devices



Height measuring instruments

From manual to motorized: Height measuring instruments as well as scribing instruments for simple or complex 2D measurements



#### Optical metrology/ microscopes

From observation to measuring microscopes, profilometers and confocal microscopes through to white light interferometry

MarSurf | Optical solutions





**Contour metrology** Portfolio of tactile handheld metrology through to optical 3D measuring systems to measure the tightest tolerances



Form and position metrology

Various systems for testing form and position tolerances – manual or fully automated upon request



**Dimensional metrology** From tactile and optical shaft measuring machines through to multisensor complete systems for rotationally symmetrical workpieces



**Roughness metrology** 

The entire range regardless of whether mobile or stationary, optical or tactile, manual or automated

# Metrology to measure us by

For more than 160 years the name "Mahr" has stood for highly accurate measuring and sophisticated technology. The objective has always been to make measuring tasks as easy as possible for users. Using the highest quality devices and systems. Providing reliable and informative measuring results for the research and industry sectors. Our intelligent functions are implemented across all systems so that users can get running quickly and intuitively. Due to its many years of expertise, Mahr is actively involved in all standardization bodies and is thus helping to further develop international metrology. This is just one of the reasons why we can guarantee that all of our systems and components are the most up-to-date. Measure us. We measure ourselves based on your requirements.

# Traceability of results and auditability

 Acceptance of all measuring systems in accordance with international guidelines and certified standards

## Environmental awareness

- Environmentally-friendly materials as well as auxiliary and operating materials
- Energy-optimized measuring instruments
- O Corporate environment management

### Standard-compliant

- Actively involved in international bodies to standardize optical measuring tasks
- Further development of our devices based on current standards
- Highest standard conformity of our measuring results

### Qualified customer service team

- Comprehensive range of services with short and reliable reaction times tailored to the specific requirements of your application area.
- Continuous and regular maintenance of your measuring systems by our qualified service staff ensuring the highest level of precision and durability of your measuring system.
- Various service packages to ensure continuous, smooth operation



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